

Optical Metrology and a Digital Optical Technologies (DOT)

Veranstaltung - Optical Metrology and a Digital Optical Technologies (DOT)

Titel	Optical Metrology and a Digital Optical Technologies (DOT)
Wann	Mo, 26. Juni 2017 - Do, 29. Juni 2017

Beschreibung

We would like to draw your attention to our well-known 2-year SPIE conference

Optical Metrology and a new SPIE conference Digital Optical Technologies (DOT)

both co-located with Laser Munich in Munich, Germany, June 26-29, 2017, and take this opportunity to invite you to submit and present your latest research at this high-quality meetings.

The conferences links can be found by following links:

<http://spie.org/conferences-and-exhibitions/optical-metrology>

<https://spie.org/conferences-and-exhibitions/digital-optical-technologies>

Lokalität - Neue Messe München

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